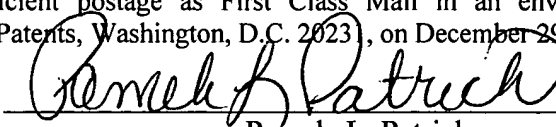
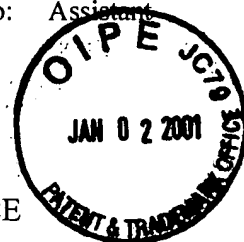


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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on December 29, 2000.

  
Pamela L. Patrick



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT application of )  
Shunpei YAMAZAKI et al. ) Group Art Unit: 2811  
Serial No. 09/295,607 ) Examiner: S. Loke  
Filed: April 22, 1999 )  
For: SEMICONDUCTOR DEVICE HAVING )  
ALUMINUM NITRIDE FILM ) Date: December 29, 2000

**AMENDMENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

**BEST AVAILABLE COPY**

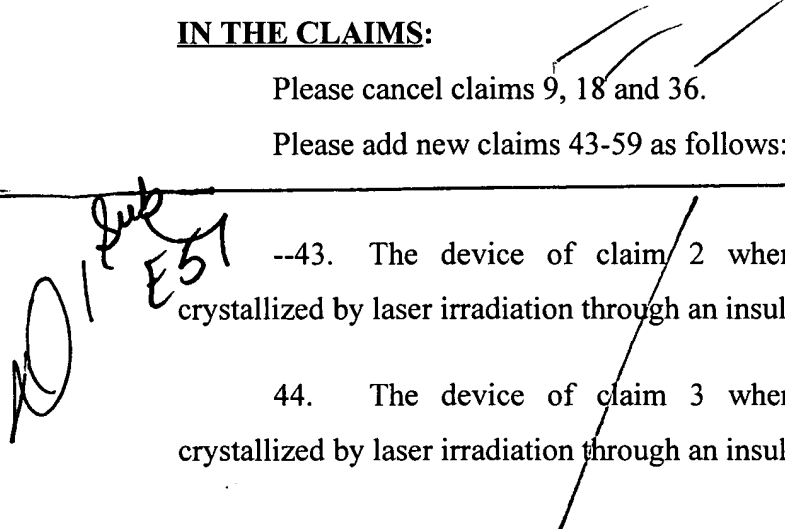
Sir:

In response to the Office Action of September 29, 2000, please amend the above-identified application as follows.

**IN THE CLAIMS:**

Please cancel claims 9, 18 and 36.

Please add new claims 43-59 as follows:

  
--43. The device of claim 2 wherein said channel formation region is crystallized by laser irradiation through an insulating film.

44. The device of claim 3 wherein said channel formation region is crystallized by laser irradiation through an insulating film.

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02 FC:103 234.00 CH